IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Wang

Application No.: 10/723,746

Filed: 11/25/2003

Title: POLISHING COMPOSITION FOR CMP

HAVING ABRASIVE PARTICLES

Examiner:

Art Unit: 1765

L. Umez Eronini

Attorney Docket No.: 03049US

Commissioner for Patents

P.O. Box 1450

Dear Sir:

Alexandria, VA 22313-1450

RESPONSE

Entered WRCE 4/17/06 wm.

MAR 2 2 2008

In response to the Office Action of December 22, 2005, having a shortened statutory

deadline of March 22, 2006, please amend this application as follows: